

NAME: KEY

Exam #2

ELEC 5820/6820

Wed 12/2/15

Constants: $\pi = 3.14159$, $\epsilon_0 = 8.854 \text{ pF/m}$, $1\text{G} = 9.8 \text{ m/s}^2$,

Equations: $k \approx \frac{N_{\text{leg}}}{N_{\text{zig}}} \frac{Ewt^3}{L^3}$, $\text{Power} = \frac{\text{Energy}}{\text{Time}}$, $C = \frac{\epsilon_0 \epsilon_r A}{d}$, $\alpha = \frac{\Delta L / L}{\Delta T}$, $Q = CV$

$$E_c = \frac{CV^2}{2}, \quad F_{GCA} = \frac{n\epsilon_0 \epsilon_r A \beta V^2}{2} \left[\frac{1}{(d_1 - x)^2} - \frac{1}{(d_1 + x)^2} \right], \quad F_{PPA} = \frac{\epsilon_0 \epsilon_r AV^2}{2(x_0 - x)^2}$$

$$V_p = \sqrt{\frac{8kx_0^3}{27A\epsilon_0 \epsilon_r}}, \quad A_{\text{circle}} = (\pi)r^2, \quad d = a\left(\frac{m}{k}\right) = aS, \quad F_{CDA} = \frac{n\epsilon_0 \epsilon_r b \beta V^2}{d_0}$$

Problems:

1) Circle the item below that is NOT an application for a pn junction. (5 points):

Diode

Thermal Bimorph

Photovoltaics

Thermoelectric Cooler

2) The proof mass of an open-loop MEMS accelerometer with a sensitivity of $1 \mu\text{s}^2$ experienced a displacement of $10 \mu\text{m}$. What acceleration did it experience, in units of m/s^2 ? (5 points):

$$d = aS \rightarrow a = \frac{d}{S} = \frac{10 \times 10^{-6}}{1 \times 10^{-6}} = 10 \text{ m/s}^2$$

Match the question with an answer by writing the letter of the answer in the blank next to the question. No answer is used more than once. (20 points)

Questions

- 1) This actuator can suffer from lateral instability: C
- 2) A temperature sensor often integrated into a MEMS device: L
- 3) A technique for aligning polarized crystallites in piezoelectrics: E
- 4) A MEMS pump that uses electro-osmotic flow: J
- 5) A commonly used SMA material in MEMS: N
- 6) For a negative feedback system, the oscillation condition where $A\beta = -1$: P
- 7) In dicing a wafer, the saw lane width: H
- 8) Membranes and diaphragms are used in MEMS: I
- 9) A 2-axis resonator is often used in MEMS: A
- 10) This is used to correct a distorted optical wavefront: O

Answers to choose from

- | | |
|--------------------------|------------------------------------|
| A) Gyroscopes | J) Pressure Sensors |
| B) Joule Heater | K) FlowFET |
| C) CDA | K) PPA |
| D) Fiducial | L) PTAT |
| E) Poling | M) Pull-in Voltage |
| F) Wankel Engine | N) Nitinol |
| G) SOI | O) Adaptive Optics |
| H) Kerf | P) Barkhausen Criterion |

3) Circle the item below that is NOT used as an energy harvesting device (5 points):

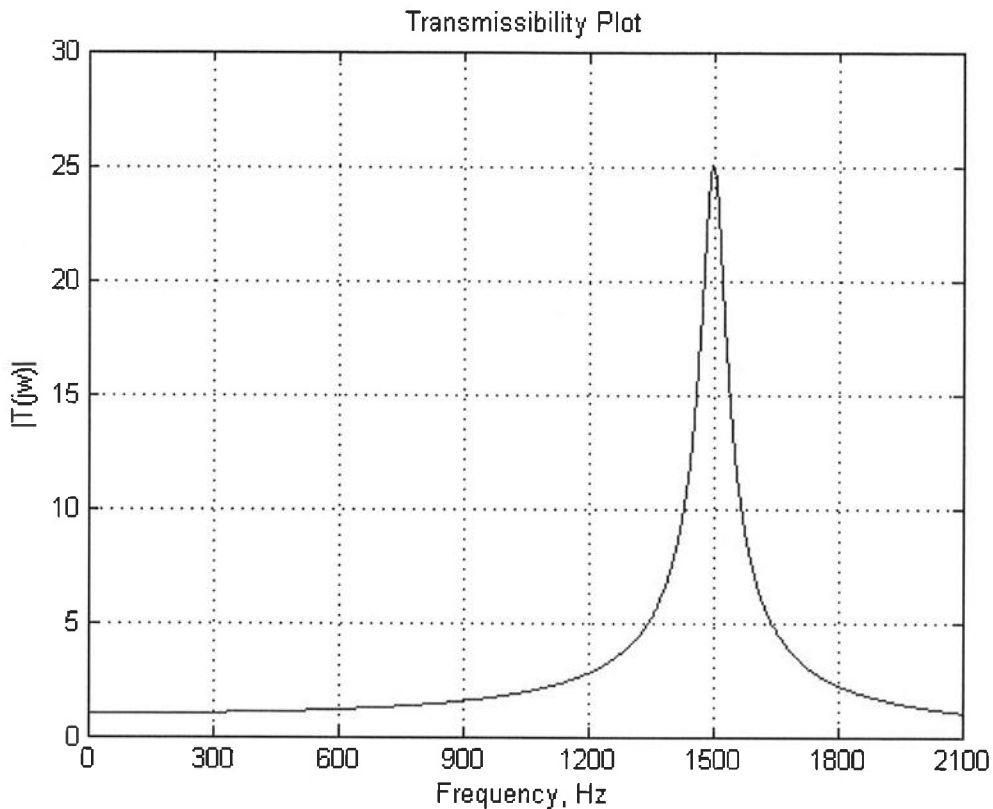
FlowFET,

TEC,

Rectenna,

PN Junction

- 4) Consider the transmissibility plot for a MEM device with a 10mg proof mass shown below and answer the following questions with regard to this device:



- (a) What is the resonant frequency, f_n (5 points)?

$$1500 \text{ Hz}$$

- (b) What is the resonant frequency, ω_n (5 points)?

$$\omega = 2\pi f = 9424.77 \text{ rad/s}$$

- (c) What is the mechanical quality factor, Q (5 points)?

$$25$$

- (d) If the frame has a displacement amplitude of $1 \mu\text{m}$ at the resonant frequency, what is the displacement amplitude of the proof mass at the resonant frequency (5 points)?

$$25 \mu\text{m}$$

- (e) What is the magnitude of $T(j\omega)$ at DC? (5 points)?

$$1$$

5) Consider the transfer function of a MEMS spring-mass-damper with a 1g proof mass:

$$T(s) = \frac{10s + 16}{s^2 + 10s + 16}$$

↳ 1×10^{-3} Kg

(a) What is the order of this system (5 points)?

2nd

(b) What is the natural frequency, ω_n (5 points)?

$$\omega_n = \sqrt{16} = 4 \text{ rad/s}$$

(c) What is the system spring constant, k (5 points)?

$$\omega_n = \sqrt{\frac{k}{m}} \rightarrow k = m \omega_n^2 = 1 \times 10^{-3} (16) = 1.6 \times 10^{-2} \text{ N/m}$$

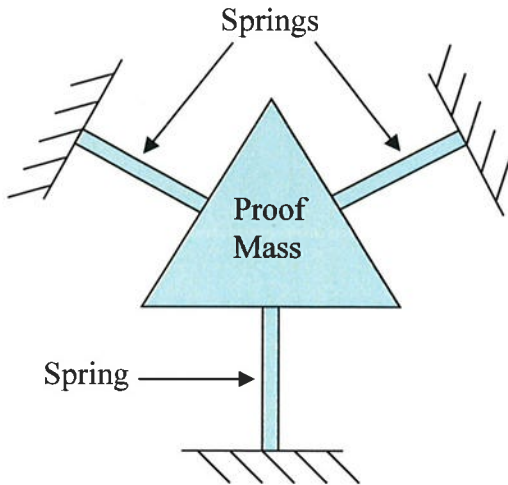
(f) What is the Quality factor, Q (5 points)?

$$\frac{\omega_n}{Q} = 10 \rightarrow Q = \frac{\omega_n}{10} = \frac{4}{10} = 0.4$$

(g) What is the damping coefficient, c (5 points)?

$$\frac{c}{m} = 10 \rightarrow c = 10m = 1 \times 10^{-2} \text{ Kg/s}$$

- 6) For the MEMS spring-mass-damper device drawn below, with all beams the same size, what is an expression for the system spring constant, k , in terms of beam (spring) dimensions (L , w and t) and the Young's Modulus (E)? (5 points)



$$k = \frac{N_{leg}}{N_{zig}} \frac{Ewt^3}{L^3} = \frac{3Ewt^3}{L^3}$$

- 7) A parallel plate actuator (PPA) consists of two square electrodes, 1mm on a side, separated by $20\mu\text{m}$, in a vacuum. The system spring constant is 25N/m and the movable electrode has a mass of $100\mu\text{g}$.

- a. What is the pull-in voltage for this actuator? (5 points)

$$V_{PI} = \sqrt{\frac{8kx_0^3}{27A\epsilon_0\epsilon_r}} = \sqrt{\frac{8(25)(20 \times 10^{-6})^3}{27(10^{-3})^2 8.854 \times 10^{-12}}} = 81.81\text{V}$$

- b. What is the stable range of motion for this actuator when it is directly connected to a DC power supply? (5 points)

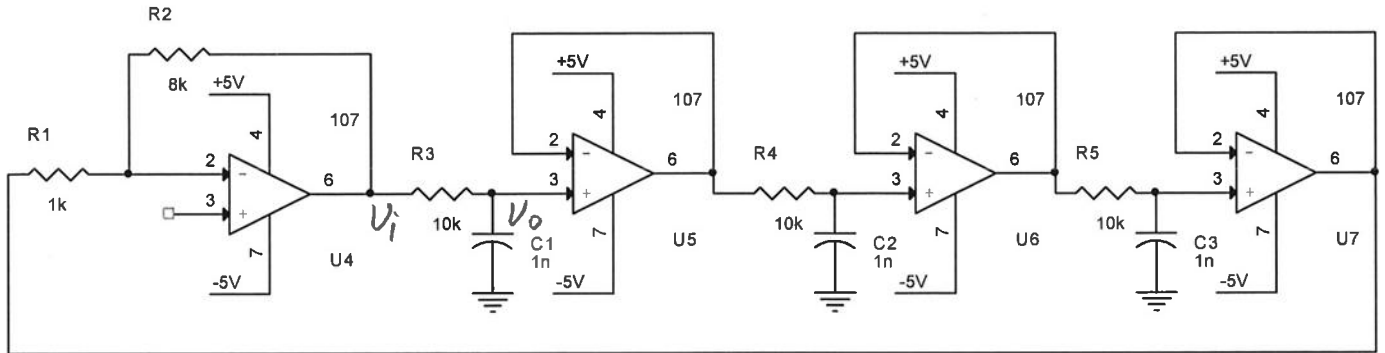
$$0 \leq x < \frac{20 \times 10^{-6}}{3} \text{ m}$$

↓

$$6.667 \mu\text{m}$$

Bonus Question (5 points)

Consider the phase shift oscillator shown below, consisting of an inverting amplifier gain stage and 3 identical RC delay stages where $R=10k\Omega$ and $C=1nF$. What is the frequency of oscillation?



$$\frac{V_o}{V_i} = \frac{1/s_c}{R + 1/s_c} = \frac{1}{R s_c + 1}$$

$$\left(\frac{V_o}{V_i} \right) = \tan^{-1}(-RC\omega) = -60^\circ \text{ for oscillation}$$

$$\therefore -RC\omega = \tan(-60^\circ)$$

$$2\pi f RC = -\tan^{-1}(-60^\circ)$$

$$f = \frac{-\tan^{-1}(-60^\circ)}{2\pi RC} = \frac{-\tan^{-1}(-60^\circ)}{2\pi (10 \times 10^3)(1 \times 10^{-9})} = 27.566 \text{ KHz}$$

Blank sheet for Calculations